

Group Art Unit:

J. Lee

Examiner:

In re patent application of

Wallace T.Y. TANG

Serial No. 08/401,229

Filed: March 9, 1995

For: IN-SITU REAL-TIME MONITORING TECHNIQUE AND APPARATUS FOR ENDPOINT

DETECTION OF THIN FILMS DURING CHEMICAL/MECHANICAL POLISHING

**PLANARIZATION** 

#### TRANSMITTAL

Assistant Commissioner for Patents Washington, D.C. 20231

#### Sir:

Transmitted herewith is an Amendment in the above-captioned application. The fee has been calculated as shown below. (Small entity fees indicated in parentheses.)

	CLAIMS AS AMENDED				/	
(1)	(2)	(3)	(4)	(5)	(6)	(7)
	Claims Remaining After Amendment		Highest Number Previously Paid For	Extra Claims	Rate	Fee
Total Claims	67	-	56	11	22.00	121.00
(Small Entity)					(11.00)	
Independent claims	14	_	12	2	80.00	80.00
(Small Entity)					(40.00)	
Multiple Dependent		_			260.00	
(Small Entity)					(130.00)	
Extension of Time	One Month		Two Months	Three Months		
Fee	\$110		\$390	\$930		
(Small Entity)	(\$55)		(\$195)	(\$465)		
Total						\$201.00

A check in the amount of the above Total Fee is attached. This amount is believed to be correct; however, the Commissioner is hereby authorized to charge any deficiency or credit any overpayment to Deposit Account No. 19-0741.

Respectfully submitted,

Date: <u>July 28, 1997</u>

Stephen B. Maebius Registration No. 35,264

FOLEY & LARDNER
3000 K Street, N.W., Suite 500
Washington, DC 20007-5109

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Attorney Docket No. 50169/105/

In re patent application of

Wallace T.Y. TANG

Group Art Unit: 2501

Serial No. 08/401,229

Examiner: J. Lee

Filed: March 9, 1995

For:

IN-SITU REAL-TIME MONITORING TECHNIQUE AND APPARATUS FOR ENDPOINT DETECTION OF THIN FILMS DURING

CHEMICAL/MECHANICAL POLISHING PLANARIZATION

# AMENDMENT AND REQUEST FOR RECONSIDERATION UNDER 37 C.F.R. § 1.111

Assistant Commissioner for Patents Washington, D.C. 20231

Sir:

In response to the outstanding Office Action mailed on April 28, 1997, please amend the above-identified application as follows:

## IN THE CLAIMS

Please cancel aim 74 without prejudice or disclaimer to the subject matter.

Please amend the following:

In claim 52, line 1, change "47" to --48--. In claim 59, line 2, change "uncouples" to --decouples--.

Please rewrite the following claims:

61. (amended) A chemical mechanical polisher for planarizing a film on one side of a substrate having two sides comprising at least one light source that transmits light through the substrate from the side of the substrate without the felm to at least one section on the film creating at least one reflected light signal that is received by at least one devices that

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